

a second position detector which detects a position of said second portion in said predetermined first direction, said second position detector being optically connected to said second portion.

2. (Amended) The stage device according to claim 1, further comprising:

a stage controller which controls said drive mechanism based on detection results obtained by said first position detector and said second position detector.

5. (Amended) An exposure apparatus which transfers a pattern of a mask onto an object, comprising:

an object stage which has a first portion to support said object and a second portion;

a drive mechanism which drives said object stage in at least a first direction, at least part of the drive mechanism being coupled to the second portion;

a first position detector which detects a position of said first portion in a predetermined first direction, said first position detector being optically connected to said first portion; and

a second position detector which detects a position of said second portion in said predetermined first direction, said second position detector being optically connected to said second portion.

6. (Amended) The exposure apparatus according to claim 5, further comprising:

a stage controller which controls the drive mechanism based on a detection result obtained by said first position detector and said second position detector.

10. (Amended) The exposure apparatus according to claim 5, further comprising a second drive mechanism which drives said object in a direction different from said first direction.

11. (Amended) An exposure device which exposes a pattern of a mask onto a substrate, comprising:

a mask stage which positions said mask;

a substrate stage which positions said substrate;

a position detecting device which detects a position of at least one of said mask stage and said substrate stage, said position detecting device having a moving mirror fixed to at least one of said mask stage and said substrate stage, and a fixed mirror fixed to a reference unit;

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a correction device which corrects for differences which result from vibration of said fixed mirror; and

a control device which controls the position of said mask stage and said substrate stage in at least one direction based on an output from said correction device.

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13. (Amended) The exposure device according to claim 11, wherein said position detecting device detects the position of at least one of said mask stage and said substrate stage based on light reflected by the fixed mirror, and light which is reflected by the moving mirror.

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15. (Amended) The exposure device according to claim 13, wherein said correction device corrects for said error based on stage instruction signals which dictate movement of said mask and substrate stages.

16. (Amended) A method of manufacturing an exposure device, comprising the steps of:

providing a stage device having a first stage which movably supports an object;

providing a drive mechanism which drives said first stage in at least a first direction, said first stage having a first portion coupled to said drive mechanism and a second portion for supporting said object, said first stage device including a first position measuring device which measures a position of said first portion in a predetermined measurement direction; and

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cont providing a first stage control system which controls said drive mechanism to control the position of said object in said at least a first direction based on a measurement result obtained by said first position measuring device.

Please add the following claims 17-26:

ab --17. (New) A method of detecting a position of a stage device that includes a movable stage which has a first portion to support an object, a second portion and a drive mechanism which drives the movable stage in at least a first direction, at least part of the drive mechanism being coupled to the second portion, comprising the steps of:

detecting a position of the first portion in a predetermined first direction with a first position detector that is optically connected to the first portion; and

detecting a position of the second portion in the predetermined first direction with a second position detector that is optically connected to the second portion.--

--18. (New) The method according to claim 17, further comprising:

controlling the drive mechanism based on detection results obtained by the first position detector and the second position detector.--

--19. (New) The method according to claim 17, wherein the first portion and the second portion are integrally formed.--

--20. (New) The method according to claim 17, wherein the drive mechanism comprises a linear motor.--

--21. (New) A method of detecting a position of an exposure apparatus which transfers a pattern of a mask onto an object and that includes an object stage which has a first portion to support the object, a second portion and a drive mechanism which drives the object stage in at least a first direction, at least part of the drive mechanism being coupled to the second portion, the method comprising the steps of:

detecting a position of the first portion in a predetermined first direction with a first position detector that is optically connected to the first portion; and

detecting a position of the second portion in the predetermined first direction with a second position detector that is optically connected to the second portion.--

--22. (New) The method according to claim 21, further comprising:

controlling the drive mechanism based on a detection result obtained by the first position detector and the second position detector.--

--23. (New) The method according to claim 21, wherein the exposure apparatus is a scanning type exposure apparatus which transfers the pattern while causing the mask and the object to move simultaneously.--

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--24. (New) The method according to claim 22, wherein the exposure apparatus includes a projection system which projects the pattern onto the object, the projection system disposed between the mask and the object.--

--25. (New) The method according to claim 24, further comprising driving the object along an axis direction of the projection system with a second drive mechanism.--

--26. (New) The method according to claim 21, further comprising driving the object in a direction different from the first direction with a second drive mechanism.--

REMARKS

Claims 1-26 are pending. By this Amendment, claims 1, 2, 5, 6, 10, 11, 13, 15 and 16 are amended, and claims 17-26 are added. The attached Appendix includes marked-up copies of each rewritten claim (37 C.F.R. §1.121(c)(1)(ii)).

The claims are amended to correct typographical informalities and to improve their grammar. Applicants submit that the amendments to the claims do not narrow the claims. Claims 17-26 are method claims based upon claims 1-10. Accordingly, no new matter is added by the above amendments.

The Examiner is requested to consider the reference submitted with the attached Information Disclosure Statement.